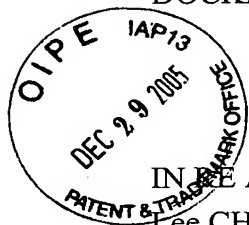


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IPW



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF:

Lee CHEN

SERIAL NO: 10/501,987

GROUP: 1763

FILED: June 6, 2005

EXAMINER: Allan W. OLSEN

FOR: PLASMA ETCHING OF NI-CONTAINING MATERIALS

LETTER

Mail Stop DD
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P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Submitted herewith is an International Written Opinion for the Examiner's consideration. The reference(s) cited therein have been previously filed with the International Search Report in an Information Disclosure Statement submitted to the U.S. Patent and Trademark Office on July 21, 2004.

Respectfully Submitted,

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